

10064703
08/08/02

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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL. NUM.	FILING DATE	CLASS	SUBCLASS	GAU
10064703	08/08/2002	427	248	1762

EXAMINER

Meeks

**APPLICANTS: Lin Frank;

**CONTINUING DATA VERIFIED:

THM Nov

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** FOREIGN APPLICATIONS VERIFIED:

THM Nov

PG-PUB	DO NOT PUBLISH <input type="checkbox"/>	RESCIND <input type="checkbox"/>	
Foreign priority claimed 35 USC 119 conditions met Verified and Acknowledged Examiners's initials		<input type="checkbox"/> yes <input checked="" type="checkbox"/> no <input type="checkbox"/> yes <input checked="" type="checkbox"/> no	ATTORNEY DOCKET NO 9458-US-PA
TITLE : Method for depositing thin film using plasma chemical vapor deposition U.S.DEP'T. OF COMM./PAT & TM-PTO-436L(Rev. 12-94)			

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		DRAWING		
Amount Due	Date Paid	Sheets Drwg.	Figs.Drwg.	Print Fig.
TERMINAL		Primary Examiner		
DISCLAIMER		PREPARED FOR ISSUE		Application Examiner
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